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Inventor: TSAI-FU CHANG, ET AL.)
Serial No: 10/673,359) Attorney Docket No.: MIC900457-DIV
Filed: September 30, 2003)
Title: STRUCTURE FOR PREVENTING SALICIDE BRIDGING AND METHOD THEREOF)))

SUBMISSION OF REVOCATION OF POWER OF ATTORNEY AND GRANT OF POWER OF ATTORNEY

Assistant Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Applicants hereby submit the attached Revocation of Power of Attorney and Grant of Power of Attorney in the above-identified application. Should there be any questions with respect to this submission a representative of the Patent Office is requested to contact the undersigned.

Respectfully submitted,

HUNG-SUI LIN ET AL.

Date: January 18, 2005

By:

Poh C. Chua

Registration No. 44,615

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PCC/lrhj

Customer No. 28970

JAN 1 8 2005

PATENT Customer No. 28970

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Patent Application and Patent Numbers:

See attached "Schedule A"

REVOCATION OF POWER OF ATTORNEY AND GRANT OF NEW POWER OF ATTORNEY

The undersigned, a representative authorized to sign on behalf of the assignee owning all of the interest in the listed and pending patent applications and issued patents on the attached sheet (Schedule A), hereby revokes all previous powers of attorney or authorization of agent granted in these patents before the date of execution hereof and appoints all the attorneys associated with Customer Number 28970.

Correspondence in this matter should be directed to:

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Date: January 10, 2005

MACRONIX INTERNATIONAL CO., LTD.

Name

Title: Dire ofor

stor of IP & Legal Office

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SCHEDULE A

	مرونت	SCHEDULE A		C-3-20
SERIAL NUMBER	FILING DATE	THE THE THE	PATENT NUMBER	ISSUE DATE
		Ono Interpoly Dielectric Flor Flash		
		Memory Cells and Method for		
		Fabricating The Same Using a		
		Single Wafer Low Temperature		
10/237,668	9/10/2002	Deposition Process	6,777,764	8/17/2004
70.201,000		Method for Removing Fences		
	1	Without Reduction of Ono Film		
10/230,328	8/29/2002	Thickness	6,677,255	1/13/2004
10/200,020	0,20,2002	Programming A Flash Memory	-,,	
10/230,666	8/29/2002	Cell	6,760,257	7/6/2004
10/200,000	0,20,2002		0,100,201	170/2001
		Apparatus and Method for		
10/426,833	5/1/2003	, · ·	6,787,860	9/7/2004
10/420,033	3/1/2003	I I I I I I I I I I I I I I I I I I I	0,707,000	3/1/2004
		Protection Layer to Prevent Under-		
40/076 600	2/19/2002	Layer Damage During Deposition	6,573,177	6/3/2003
10/076,629	2/19/2002	Sensing Method for EEPROM	0,573,177	0/3/2003
40/454 450	E /04 /0000	Refresh Scheme	6 620 920	10/20/2002
10/151,150	5/21/2002	Semiconductor Device with	6,639,839	10/28/2003
				·
10/10/1000	0/04/0000	Minimal Short-Channel Effects and	0.555.044	4/00/0000
10/101,930	3/21/2002	Low Bit-Line Resistance	6,555,844	4/29/2003
		Sonos Component Having High		40/04/0000
10/101,922	3/21/2002	Dielectric Property	6,498,377	12/24/2002
		Method for Forming An Oxide		
10/101,931	3/21/2002	Layer on a Nitride Layer	6,551,879	4/22/2003
		Structure for Preventing Salicide		
10/186,619	7/2/2002	Bridging and Method Thereof	6,677,199	1/13/2004
		Method of Preventing Tungsten		
10/132,286	4/26/2002	Plugs From Corrosion	6,703,301	3/9/2004
		Method for Forming A Phase		-
10/197,896	7/19/2002	Change Memory	6,759,267	7/6/2004
		Memory Device and Operation		
10/214,770	8/9/2002	Thereof	6,788,602	9/7/2004
		Method for Forming A Phase		
10/847,277	5/17/2004		N/A	NA
		Neural Network for Determining		
10/176,065	6/21/2002		N/A	NA
		Photoresist Pump Dispense		
10/387,489	3/14/2003		N/A	NA
		Cleaning Systems With Monitaring		
10/439,014	5/16/2003	Functions	N/A	NA
10/600,700	6/23/2003	Peer Version Control System	N/A	NA
10/667,447	9/23/2003	Batch Order Change System	N/A	NA
·	-	Elimination of the Fast-Erase		*
10/733,230	12/12/2003	Pheonomena in Flash Memory	N/A	NA
		Cleaning Method Using Ozone DI		<u> </u>
10/731,150	12/10/2003	-	N/A	NA
, , • •		Endpoint Detection in		
		Manufacturing Semi-Conductor		
10/685,484	10/16/2003	_	N/A	NA
10,000,707	10/10/2000		1 7/7 1	

SERIAL NUMBER	FILING DATE	TITLE	PATENT NUMBER	ISSUE DATE
		Program/Erase Method for P-		
		Channel Charge Trapping Memory		
10/857,866	6/2/2004	Device	N/A	NA
		Mathed for Reducing Dimensions	,	
	0.000.000	Method for Reducing Dimensions	AL/A	INIA .
10/465,852	6/20/2003	Between Patterns on a Hardmask	N/A	NA
		Method for Reducing Dimensions		
10/739,049	12/19/2003	Between Patterns on a Photoresist	N/A	NA
107700,010	12	Structure for Preventing Salicide		
10/673,359	9/30/2003	Bridging and Method Thereof	N/A	NA
. 6. 6. 7 5 7 5 7 5 7 5 7 5 7 5 7 5 7 5 7 5 7		Non-Volatile Memory Cell and		
10/873,142	1/14/2004	Operating Method	N/A	NA
		Memory Device With Built-In Error-		
10/237,082	6/2/2003	Correction Capabilities	N/A	NA
		Memory Device With Built-In Error-		
10/449,590	6/2/2003	Correction Capabilities	N/A	NA
		Semi-Conductor Device With		
		Minimal Short-Channel Effects and		
10/361,681	2/11/2003	Low Bit-Line Resistance	N/A	NA
		Method of Forming a Polysilicon		
		Layer Compressing		
10/715,558	11/19/2003	Microcrystalline Grains	N/A	NA
10/414,048	4/16/2003	ONO Dielectric for Memory Cells	N/A	NA
		Method of Integrating The	V	
		Fabrication Process for Integrated		
10/418,121	4/18/2003	Circuits and Mem Devices	N/A	NA
		Method for Controlling a Butterfly		
10/387,487	3/14/2003	Valve	N/A	NA
10/653,892	9/4/2003	A Non-Volatile Flash Memory	N/A	NA
		Fabrication Method of Sub-		
		Resolution Pitch for Integrated		
10/703,453	11/10/2003	Circuits	N/A	NA
		Method for Reducting Dimensions		
00/070 546	10/10/2001	Between Patterns on a Photoresist	NI/A	NA
09/978,546	10/18/2001	Method for Eliminating Standing	11//	INA
10/177 1/15	6/24/2002	Waves in a Photoresist Profile	N/A	NA
10/177,145	0/24/2002	Method for Detecting Solvent	19//	
•		Leakage During Manufacture of a		
10/241,486	9/12/2002	Semi-Conductor Device	N/A	NA
10/241,400	3/ 12/2002	Memory Device and Method of		147.
10/223,327	8/20/2002	Manufacturing The Same	N/A	NA
TOTALO, OLI	0,20,2002	Method of Fabricating ONO		
		Dielectric for Non-Volatile		
10/376,225	3/3/2003	Memories	N/A	NA
		Method of Forming An Embedded		
10/387,488	3/14/2003	ROM	N/A	NA
		Defect Reduction Using Pad	-	
10/681,099	10/9/2003	Conditioner Cleaning	N/A	NA

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SERIAL NUMBER	FILING DATE	SAN SAN STATE OF THE SAN	PATENT NUMBER	ISSUE, DATE
		Method of Preventing Over-Erase		
		of Memory Devices	İ	
		Method for Eliminating Standing		
10/176,061	6/21/2002	Waves in a Photoresist Profile	N/A	NA
		Self-Aligned Patterning in Dual		
10/076,630	2/19/2002	Damascene Process	N/A	NA
		Method for Forming Tungsten		
		Plugs to Prevent Corrosion		
10/137,406	5/3/2002	Complexity	N/A	NA
		Method for Forming Self-Aligned		
10/186,892	7/2/2002	Salicides	N/A	NA
		Method for Reduced Photoresist		
10/210,032	8/2/2002	Usage	N/A	NA
		Method of Forming Self-Aligned		
10/403,060	4/1/2003	Contracts	N/A	NA
10, 100,000		Method for Suppressing Boron		
		Penetration by Implantation in P*		
10/656,224	9/8/2003	Mosfets	N/A	NA
10,000,2221	0.0.200	Non-Volatile Memory Cell and		
10/756,777	1/14/2004	Operating Method	N/A	NA -
1000,		Sub-90nm Space and Hole		
		Patterning Using 248nm		
		Lithography with Plasma-		
60/390,183	6/21/2002	Polymerization Coating	N/A	NA
00/000,100	0.22002	Method for Eliminating Polycide		
		Voids Through Nitrogen		
		Implantation	N/A	NA
		Method for Reducing Dimensions		·
10/465,848	6/20/2003	Between Patterns on a Photomask	N/A	NA
	0,20,200	Method of Modulating Threshold		
10/417,105 4	4/17/2003		N/A	NA
		Method for Forming Shallow	<u>,</u>	
		Trench Isolation With Control of		
10/385,483	3/12/2003		N/A	NA
		Method for Plymer Removal After		
10/376,229	3/3/2003		N/A	NA
		Method for Shrinking Dimensions		
10/465,850	6/20/2003	_	N/A	NA
		Method and System for		
		Lithography Using Phase-Change		
10/315,003			N/A	NA